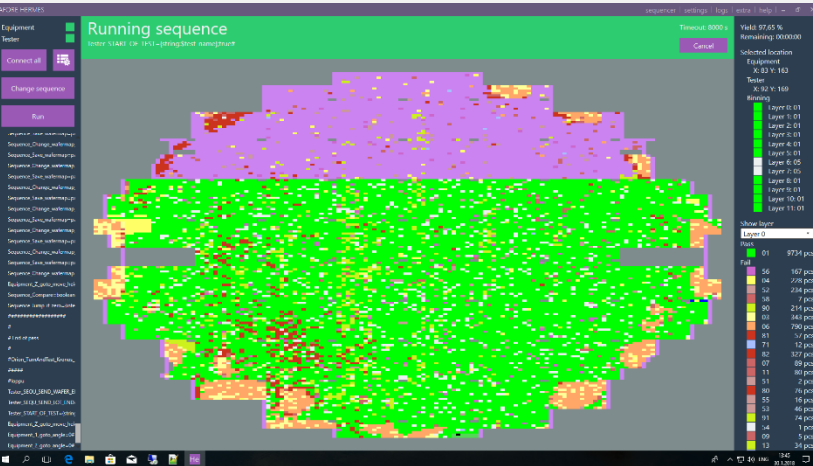
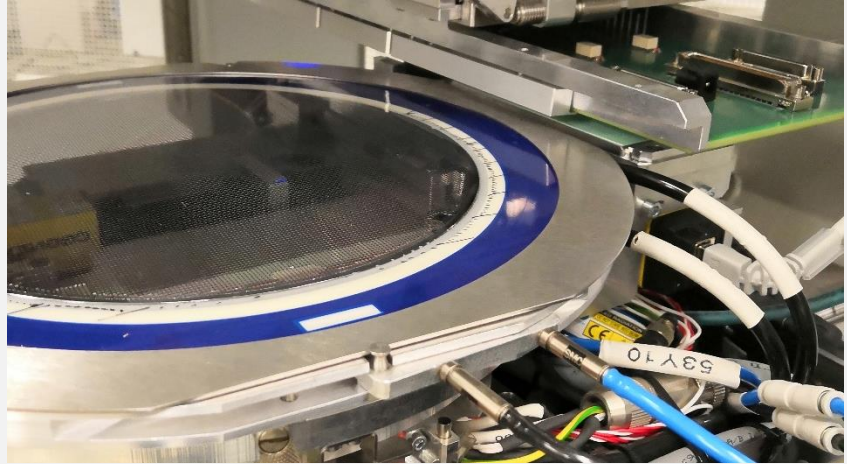




More than 20 years of application specific test solutions for MEMS and semiconductors

Wafer and frame probing equipment for

- R&D
- Wafer Sort and
- Final Test



Real stimulus for calibration of

Barometric pressure sensors

TPMS sensors

Vacuum sensors

Accelerometers

Gyroscopes and

E-compass devices

Options include:

- Temperature -40°C to 150°C
- Vacuum $\geq 10^{-2}$ mbar (abs)
- Pressure ≤ 2 bar (abs)
- Low g-acceleration max ± 1 g
- Infinite rotation yaw-rate max $750^{\circ}/\text{s}$
- Magnetic field stimulus ≤ 1 mT

